

Search Terms	
1	ALIGN
2	ALIGNED
3	ALIGNEDS
4	ALIGNING
5	ALIGNINGS
6	ALIGNMENT
7	ALIGNMENTS
8	ALIGNS
9	CALIBRATE
10	CALIBRATED
11	CALIBRATES
12	CALIBRATING
13	CALIBRATINGS
14	CALIBRATION
15	CALIBRATIONS
16	COMPENSATE
17	COMPENSATED
18	COMPENSATEDS
19	COMPENSATES
20	COMPENSATING
21	COMPENSATINGS
22	COMPENSATION
23	COMPENSATIONS
24	CRUCIFORM
25	CRUCIFORMS
26	PATTERN
27	PATTERNS
28	PRODUCTION
29	SCANNED
30	SCANNER
31	SCANNERS
32	SCANNING
33	SCANNINGS
34	STEPPED
35	STEPPER
36	STEPPERS
37	STEPPING
38	STEPPINGS

	Total	USPAT	US-PGPUB	EPO	JPO	Derwent	IBM TDB	USOCR
1	286630							
2	882954							
3	1							
4	200145							
5	5							
6	650883							
7	20697							
8	70479							
9	53664							
10	118721							
11	5670							
12	48065							
13	1							
14	157988							
15	8972							
16	361296							
17	188484							
18	1							
19	89640							
20	184756							
21	2							
22	240702							
23	3324							
24	11121							
25	137							
26	1287322							
27	484469							
28	1703340							
29	191767							
30	171097							
31	33588							
32	490421							
33	2171							
34	191181							
35	44703							
36	2829							
37	92223							
38	133							

Search Terms	
39	WAFER
40	WAFERS
41	PROD N
42	(((((STEPPER OR STEPPING OR STEPPED) AND (((CALIBRATE OR CALIBRATING OR CALIBRATED OR COMPENSATED OR COMPENSATING OR COMPENSATE OR CALIBRATION OR COMPENSATION) SAME WAFER) SAME (CRUCIFORM OR PATTERN)))) AND (WAFER SAME PRODUCTION)) AND (SCANNED OR SCANNER OR SCANNING)) AND (ALIGNING OR ALIGN OR ALIGNED OR ALIGNMENT))

	Total	USPAT	US-PGPUB	EPO	JPO	Derwent	IBM TDB	USOCR
39	330653							
40	108102							
41	518450							
	104	68	35	0	0	1	0	
42								

	U	1	D cument ID	Issue Date	Pages	Title	Current OR
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20040114132 A1	20040617	10	Test pattern, inspection method, and device manufacturing method	356/124
2	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040114121 A1	20040617		Exposure apparatus, exposure method using the same, and method of manufacture of circuit device	355/67
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040109148 A1	20040610	22	Exposure apparatus	355/52
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040102912 A1	20040527		AUTOMATIC CALIBRATION OF A MASKING PROCESS SIMULATOR	702/94
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040082085 A1	20040429		Method for aligning and exposing a semiconductor wafer	438/16
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040060910 A1	20040401		High speed, laser-based marking method and system for producing machine readable marks on workpieces and semiconductor devices with reduced subsurface damage produced thereby	219/121.69
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040051855 A1	20040318		Programmable photolithographic mask system and method	355/53
8	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040031779 A1	20040219		Method and system for calibrating a laser processing system and laser marking system utilizing same	219/121.83
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20040001192 A1	20040101		System and method for automated focus measuring of a lithography tool	355/55
10	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030237064 A1	20031225		Characterization and verification for integrated circuit designs	716/5
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030223630 A1	20031204		Overlay metrology and control method	382/145
12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030202174 A1	20031030		Method and apparatus for self-referenced projection lens distortion mapping	356/124
13	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030190070 A1	20031009		Pattern forming method	382/145
14	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030115569 A1	20030619		Method and system for optical proximity correction	716/19
15	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030104640 A1	20030605		Method for improving substrate alignment	438/14
16	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030095267 A1	20030522		Focus masking structures, focus patterns and measurements thereof	356/614
17	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030090661 A1	20030515		Focusing method, position-measuring method, exposure method, method for producing device, and exposure apparatus	356/400
18	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030082463 A1	20030501		Method of two dimensional feature model calibration and optimization	430/5

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
1			Den Boef, Arie Jeffrey et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20040114132	<input type="checkbox"/>
2			Nishi, Kenji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
3	355/53; 355/67; 355/71		Shima, Shinichi	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20040109148	<input type="checkbox"/>
4			Ivanovic, Lav et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
5			Rossiger, Martin et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
6	219/121.83		Schramm, Rainer	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
7			Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
8	347/224; 700/166		Canill, Steven P. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
9	355/52; 355/67; 356/400		Lyons, Joseph H. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
10	716/19		White, David et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
11			Adel, Michael et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
12	356/401; 430/22		Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
13			Ando, Atsushi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
14	716/21		Ikeuchi, Atsuhiko	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
15			Ziger, David H.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
16			Mieher, Walter Dean et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
17			Kobayashi, Mitsuru	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
18	430/30		Laidig, Thomas et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
19	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030025893 A1	20030206	23	Projection exposure apparatus and projection exposure method	355/53
20	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020183989 A1	20021205	26	Overlay error model, sampling strategy and associated equipment for implementation	703/2
21	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020176062 A1	20021128	39	Programmable photolithographic mask system and method	355/53
22	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020148975 A1	20021017	99	Apparatus for inspection with electron beam, method for operating same, and method for manufacturing semiconductor device using former	250/492.1
23	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020130262 A1	20020919	107	Method for inspecting substrate, substrate inspecting system and electron beam apparatus	250/311
24	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020105649 A1	20020808	35	Method and apparatus for self-referenced wafer stage positional error mapping	356/401
25	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020102482 A1	20020801	33	Reference wafer and process for manufacturing same	430/22
26	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020071112 A1	20020613	29	Method and apparatus for self-referenced projection lens distortion mapping	356/124
27	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020039828 A1	20020404	13	Method for exposing a layout comprising multiple layers on a wafer	438/401
28	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020036264 A1	20020328		Sheet beam-type inspection apparatus	250/306
29	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020033449 A1	20020321		Inspection system by charged particle beam and method of manufacturing devices using the system	250/306
30	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020028399 A1	20020307		Inspection system by charged particle beam and method of manufacturing devices using the system	430/30
31	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020027647 A1	20020307		Photolithographic system for exposing a wafer using a programmable mask	355/53

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
19	250/548; 355/55; 355/67; 356/399; 356/400; 356/401		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030025893	<input type="checkbox"/>
20			Chien, Chen-Fu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020183989	<input type="checkbox"/>
21	355/69; 355/77; 359/224; 359/855		Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020176062	<input type="checkbox"/>
22			Kimba, Toshifumi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020148975	<input type="checkbox"/>
23			Nakasuji, Mamoru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020130262	<input type="checkbox"/>
24			Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020105649	<input type="checkbox"/>
25	430/30; 430/313; 430/329		Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020102482	<input type="checkbox"/>
26			Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020071112	<input type="checkbox"/>
27			Hahmann, Peter et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020039828	<input type="checkbox"/>
28			Nakasuji, Mamoru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
29			Nakasuji, Mamoru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
30	250/306; 356/237.5; 430/296		Nakasuji, Mamoru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
31	355/67; 355/69; 355/71; 359/224; 359/855; 430/5; 430/55		Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
32	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010046631 A1	20011129		Divided reticles for charged-particle-beam microlithography apparatus, and methods for using same	430/5
33	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010043321 A1	20011122		Exposure apparatus, exposure method using the same, and method of manufacture of circuit device	355/67
34	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010038958 A1	20011108		Method for evaluating lithography system, method for adjusting substrate-processing apparatus, lithography system, and exposure apparatus	430/30
35	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010036588 A1	20011101		Lithographic imaging of a structure pattern onto one or more fields on a substrate	430/201
36	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6737207 B2	20040518		Method for evaluating lithography system and method for adjusting substrate-processing apparatus	430/30
37	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6734971 B2	20040511		Method and apparatus for self-referenced wafer stage positional error mapping	356/401
38	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6727978 B2	20040427		Projection exposure apparatus and projection exposure method	355/53
39	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6716649 B2	20040406		Method for improving substrate alignment	438/14
40	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6708131 B1	20040316		Wafer alignment system	702/95
41	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6700950 B1	20040302		Methods and systems for controlling critical dimension (CD) error	378/34
42	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6699627 B2	20040302		Reference wafer and process for manufacturing same	430/22
43	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6673638 B1	20040106		Method and apparatus for the production of process sensitive lithographic features	438/14
44	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6635395 B2	20031021		Method for exposing a layout comprising multiple layers on a wafer	430/22
45	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6627365 B1	20030930		Photomask and projection exposure apparatus	430/30

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
32	250/492.2; 250/492.3; 430/296; 430/942		Fujiwara, Tomoharu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
33	355/53; 355/55; 355/68; 355/69; 355/71; 355/77		Nishi, Kenji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
34	355/18		Imai, Yuji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
35			Buschbeck, Herbert et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
36			Imai, Yuji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
37			Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
38	355/67; 355/72		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
39			Ziger, David H.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
40			Laursen, James W. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
41	382/145		Pellegrini, Joseph et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
42	430/30		Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
43	438/15		Bendik, Joseph J. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
44	430/296; 430/30; 430/312; 430/328; 430/942		Hahmann, Peter et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
45	430/311; 430/396; 430/5		Shiraishi, Naomasa	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
46	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6603529 B1	20030805		Monitoring apparatus and method particularly useful in photolithographically processing substrates	355/27
47	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6600551 B2	20030729		Programmable photolithographic mask system and method	355/53
48	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6573986 B2	20030603		Method and apparatus for self-referenced projection lens distortion mapping	356/124
49	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6562639 B1	20030513		Utilizing electrical performance data to predict CD variations across stepper field	438/14
50	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6552776 B1	20030422		Photolithographic system including light filter that compensates for lens error	355/67
51	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6500591 B1	20021231		Method of averaging focus through scattered energy determination	430/30
52	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6480261 B2	20021112		Photolithographic system for exposing a wafer using a programmable mask	355/53
53	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6414743 B1	20020702		Exposure apparatus, exposure method using the same and method of manufacture of circuit device	355/69
54	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6359678 B1	20020319		Exposure apparatus, method for producing the same, and exposure method	355/53
55	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6320187 B1	20011120		Magnification and rotation calibration patterns for particle beam projection system	250/252.1
56	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6291110 B1	20010918		Methods for transferring a two-dimensional programmable exposure pattern for photolithography	430/5

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
46	356/237.4; 356/237.5; 356/388; 356/630; 356/632; 396/611		Finarov, Moshe	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
47			Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
48	356/401; 430/22		Smith, Adlai et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
49			Minvielle, Anna et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
50	355/71		Wristers, Derick J. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
51			Adams, Thomas Evans	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
52	250/492.2; 250/492.22; 355/27; 355/38; 355/39; 355/40; 355/72; 358/487; 358/506; 430/5		Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
53	355/30; 355/53		Nishi, Kenji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
54	250/216; 250/492.2; 250/548; 355/30; 355/55; 355/57; 355/60; 355/67; 355/77; 359/512		Ota, Kazuya	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
55	250/491.1; 250/492.2		Enichten, William Albert	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
56			Cooper, Gregory D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
57	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6277531 B1	20010821		Charged-particle-beam microlithography apparatus and methods including focal-point correction	430/30
58	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6166801 A	20001226		Monitoring apparatus and method particularly useful in photolithographically processing substrates	355/27
59	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6147355 A	20001114		Pattern forming method	250/492.2
60	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6133986 A	20001017		Micro lens scanner for microlithography and wide-field confocal microscopy	355/67
61	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6118516 A	20000912		Projection exposure apparatus having a filter arranged in its projection optical system and method for protecting circuit patterns	355/53
62	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6019850 A	20000201		Apparatus for making a semiconductor device in a continuous manner	118/719
63	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5989764 A	19991123		Method of adjusting lithography tool through scattered energy measurement	430/30
64	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5989759 A	19991123		Pattern forming method using alignment from latent image or base pattern on substrate	430/22
65	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5985498 A	19991116		Method of characterizing linewidth errors in a scanning lithography system	430/30
66	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5981119 A	19991109		Lithography tool adjustment and semiconductor integrated circuit fabrication utilizing latent imagery	430/30
67	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5968693 A	19991019		Lithography tool adjustment utilizing latent imagery	430/30
68	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5959721 A	19990928		Projection exposure apparatus and projection exposure method	355/53
69	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5753531 A	19980519		Method for continuously making a semiconductor device	438/61
70	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5617340 A	19970401		Method and reference standards for measuring overlay in multilayer structures, and for calibrating imaging equipment as used in semiconductor manufacturing	702/85
71	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5596413 A	19970121		Sub-micron through-the-lens positioning utilizing out of phase segmented gratings	356/401

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
57	250/492.2; 250/492.3; 430/296		Mortiz, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
58	356/400; 382/145; 396/611; 414/935		Dishon, Giara et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
59	250/491.1		Ando, Atsushi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
60	355/43; 355/77		Johnson, Kenneth C.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
61	356/401		Irie, Nobuyuki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
62	118/300; 118/725; 156/345.31; 250/492.21; 430/942; 432/55		Frey, Jeffrey	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
63			Adams, Thomas Evans	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
64	430/296; 430/30; 430/942		Ando, Atsushi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
65			Levinson, Harry et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
66	430/22; 430/311		Adams, Thomas Evans	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
67			Adams, Thomas Evans	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
68	355/67; 355/71		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
69	438/484; 438/62; 438/907		Frey, Jeffrey	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
70			Cresswell, Michael W. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
71	250/548		Stanton, Stuart et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
72	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5592211 A	19970107		Laser pattern/inspector with a linearly ramped chlp deflector	347/260
73	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5563095 A	19961008		Method for manufacturing semiconductor devices	438/62
74	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5508803 A	19960416		Method and apparatus for monitoring lithographic exposure	356/243.5
75	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5362585 A	19941108		Semiconductor integrated circuit fabrication utilizing latent imagery	430/30
76	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5333049 A	19940726		Apparatus and method for interferometrically measuring the thickness of thin films using full aperture irradiation	356/504
77	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5151749 A	19920929		Method of and apparatus for measuring coordinate position and positioning an object	356/620
78	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5142132 A	19920825		Adaptive optic wafer stepper illumination system	250/201.9
79	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5095447 A	19920310		Color overlay of scanned and reference images for display	382/144
80	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5073912 A	19911217		Sample moving apparatus, sample moving system and semiconductor manufacturing apparatus	378/34
81	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5046110 A	19910903		Comparator error filtering for pattern inspector	382/149
82	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5027132 A	19910625		Position compensation of laser scan for stage movement	347/225
83	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5018212 A	19910521		Defect area consolidation for pattern inspector	382/145
84	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5018210 A	19910521		Pattern comparator with substage illumination and polygonal data representation	382/145

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image D c. Displayed	PT
72	347/255		Porter, Vernon R. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
73	118/718; 118/719; 438/484; 438/490; 438/676; 438/707; 438/907; 438/980		Frey, Jeffrey	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
74			Hibbs, Michael S. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
75	356/302; 430/311; 430/394		Adams, Thomas E.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
76	356/513		Ledger, Anthony M.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
77	250/548; 356/400; 356/401; 356/500		Tanimoto, Aikazu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
78	356/121		MacDonald, Bruce G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
79	345/965		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
80	250/491.1; 250/492.1; 414/354; 414/384; 414/754; 414/784; 414/936		Kobayashi, Isao et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
81	348/126; 382/192; 382/220		Carucci, Lori A. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
82			Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
83	348/130; 356/237.5; 382/199		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
84	382/196; 382/205		Merryman, Jerry D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
85	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5001764 A	19910319		Guardbands for pattern inspector	382/145
86	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4991977 A	19910212		Smoothing filter for stage position pulses	382/321
87	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4989255 A	19910129		Expansion of compact database for pattern inspector or writer	382/145
88	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4985927 A	19910115		Method of detecting and reviewing pattern defects	382/149
89	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4984282 A	19910108		Parallel processing of reference and guardband data	382/149
90	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4979223 A	19901218		Data handling system for pattern inspector or writer	382/149
91	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4969200 A	19901106		Target autoalignment for pattern inspector or writer	382/288
92	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4929083 A	19900529		Focus and overlay characterization and optimization for photolithographic exposure	356/400
93	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4912487 A	19900327		Laser scanner using focussing acousto-optic device	347/255
94	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4886958 A	19891212		Autofocus system for scanning laser inspector or writer	250/492.2
95	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4835392 A	19890530		Ion-projection apparatus	250/492.2
96	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4812661 A	19890314		Method and apparatus for hybrid I.C. lithography	250/491.1
97	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4728193 A	19880301		Precision automatic mask-wafer alignment system	356/509
98	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4627010 A	19861202		Method and device for discriminating stillness of a step exposure apparatus	356/400
99	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4557599 A	19851210		Calibration and alignment target plate	356/243.1
100	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4550374 A	19851029		High speed alignment method for wafer stepper	716/21

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
85	348/130; 382/199		Wood, Anthony B. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
86			Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
87	382/232		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
88	348/126; 382/201		Norwood, David A. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
89	356/237.5; 382/303		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
90	382/218		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
91	356/400; 382/294		Manns, William G. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
92	356/123		Brunner, Timothy A.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
93	347/260; 358/296		Porter, Vernon R. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
94	250/201.4; 356/3.01		Merryman, Jerry D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
95	250/398		Loschner, Hans et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
96	250/398; 250/492.2		Owen, Geraint	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
97	356/401		Bartelt, John L. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
98	257/E21.211; 356/401; 716/19; 716/21		Kosugi, Masao	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
99	125/13.01; 33/286; 348/95; 356/401; 356/73; 83/522.11		Zimring, Bruce	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
100	348/87; 348/95; 356/401; 702/94		Mesman, Boris et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
101	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4444492 A	19840424		Apparatus for projecting a series of images onto dies of a semiconductor wafer	355/55
102	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4425037 A	19840110		Apparatus for projecting a series of images onto dies of a semiconductor wafer	355/43
103	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4328553 A	19820504		Method and apparatus for targetless wafer alignment	356/139.04
104	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6708131 B	20040316		Transforming method for calibration data in wafer production apparatus, involves measuring difference between coordinates of first and second patterns to establish processing pattern alignment of production wafer	

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
101	125/35; 269/21; 355/43; 355/54; 356/139.04; 356/401; 359/730		Lee, Martin E.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
102	355/53; 355/55; 355/61; 356/139.07; 356/401; 359/629; 359/727		Hershel, Ronald S. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
103	125/13.01; 125/35; 348/126; 348/87; 348/95; 356/141.5; 356/400; 414/754; 700/172; 700/192		Fredriksen, Thorbjorn R. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
104			HICKMAN, C A et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	Search Terms
1	HICKMAN-CRAIG
2	((LAURSEN-JAMES.IN.) OR (HICKMAN-CRAIG.IN.))

	Total	USPAT	US-PGPUB	EPO	JPO	Derwent	IBM TDB	USOCR
1	2							
2	2	1	1	0	0	0	0	

	U	1	Document ID	Issue Date	Pages	Title	Current OR
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20030046786 A1	20030313	15	Spindle chuck cleaner	15/301
2	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6297877 B1	20011002	10	Methods for compensating for lens heating resulting from wafer reflectance in micro-photolithography equipment	355/77

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
1			Shirley, Paul et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030046786	<input type="checkbox"/>
2	355/53; 355/55		Hickman, Craig	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 6297877	<input type="checkbox"/>